

**AMENDMENTS TO THE CLAIMS**

1. (Canceled)

2. (Currently amended) ~~The method according to claim 1, wherein the micropattern is formed~~ A method for forming a reflective reflector pattern comprising:

forming a micropattern using an metal-containing compound through a photoreaction or thermal energy through the following steps:

(a) coating the metal-containing organometallic compound on a substrate to form a thin ~~film;~~ film,

(b) exposing the thin film to light through a mask to decompose the metal-containing organometallic compound at exposed area and to induce a difference in solubility between the exposed and unexposed areas and developing the thin film to remove the metal-containing organometallic compound of the unexposed area; ~~and area,~~ and

(c) reducing or oxidizing the exposed area to form a metal pattern or metal oxide pattern; and  
growing crystal, using the pattern as a nucleus for growing crystal, by an electro or electroless plating process.

3. (Currently amended) ~~The method according to claim 1, wherein the micropattern is formed~~ A method for forming a reflective reflector pattern comprising:

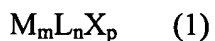
forming a micropattern using an metal-containing compound through a photoreaction or

thermal energy through the following steps:

- (a) forming a pattern using the metal-containing organometallic compound through soft lithography or ink jet ~~printing~~, and printing, and
  - (b) heating the pattern to decompose the metal-containing organometallic compound; and
- growing crystal, using the pattern as a nucleus for growing crystal, by an electro or electroless plating process.

4. (Original) The method according to claim 3, wherein the soft lithography is microcontact printing or micromolding in capillaries (MIMIC).

5. (Currently amended) The method according to ~~claim 1~~, claim 2 or 3, wherein the metal-containing organometallic compound is represented by the following formula 1:



wherein M is a ~~transition metal, lanthanide or representative element~~ metal; L is a ligand; X is a monovalent to trivalent anion; m is an integer from 1 to 10, and when m is 2 or more, each M may be different from ~~each~~ the other; n is an integer from 0 to 60, and when n is 2 or more, each L may be different from ~~each~~ the other; p is an integer from 0 to 60, and when p is 2 or more, each X may be different from ~~each~~ the other; L may act as a ligand bonding two metals when two or more metals are used; and n and p are not simultaneously 0.

6. (Currently amended) The method according to claim 5, wherein M is a late transition

metal (IX~XII) selected from the group consisting of Co, Ni, Pd, Pt, Cu, Ag, Au, Zn and Cd, or a representative element metal Al.

7. (Currently amended) The method according to claim 5, wherein L is a ligand selected from the group consisting of acetylacetonates, acetates,  $\beta$ -ketoiminates,  $\beta$ -diiminates,  $\beta$ -ketoesters, dialkyldithiocarbamates, carboxylates, oxalato, ~~halogens, hydrogen, hydroxy, cyano, nitro, nitrate, nitrosyl ( $\text{NO}^-$ ), azides, thiocyanato ( $\text{NCS}^-$ ), isothiocyanato ( $\text{SCN}^-$ ),~~ alkoxy ligands, pyridines, amines, diamines, arsines, diarsines, phosphines, diphosphines, arenes, carbonyl, imidazolylidene, ethylene, acetylene, aquo, thiocarbonyl, thioether and ~~derivatives~~ a derivative thereof.

8. (Currently amended) The method according to claim 5, wherein X is an anion selected from the group consisting of ~~halogens, halogen,~~ hydroxy, ~~cyano ( $\text{CN}^-$ ), nitro cyanide ( $\text{CN}^-$ ),~~ nitrite ( $\text{NO}_2^-$ ), nitrate ( $\text{NO}_3^-$ ), nitrosyl ( $\text{NO}^-$ ), azide ( $\text{N}_3^-$ ), thiocyanate ( $\text{NCS}^-$ ), isothiocyanate ( $\text{SCN}^-$ ), tetraalkylborate ( $\text{BR}_4^-$ , R = methyl, ethyl or phenyl group), tetrahaloborate ( $\text{BX}_4^-$ , X = F, Br), hexafluorophosphate ( $\text{PF}_6^-$ ), triflate ( $\text{CF}_3\text{SO}_3^-$ ), tosylate ( $\text{Ts}^-$ ), sulfate ( $\text{SO}_4^{2-}$ ), and carbonate ( $\text{CO}_3^{2-}$ ).

9. (Currently Amended) The method according to claim 6, wherein the metal-containing organometallic compound is ~~silver compound~~ a silver compound.

10. (Withdrawn - Currently Amended) A ~~high~~ reflective reflector pattern that is prepared

by one of methods according to ~~claims 1 to 9~~ claims 2 and 3.

11. (Withdrawn - Currently Amended) A reflective or transflective liquid crystal display device containing the ~~high~~ reflective reflector pattern according to 10.

12. (New) The method according to claim 5, wherein M is at least one transition metal, lanthanide or Al.